

Appl. No. 10/625,239
Amdt Dated Mar. 6, 2006
Reply to Office Action of Dec. 06, 2005

REMARKS

Claims Rejections under 35 U.S.C. 103(a)

Claims 1,2, 6-9, and 17-18 are rejected under 35 U.S.C. 103(a) as being unpatentable over Aoki (US Patent No. 6,041,799) and further in view of La Pan (US 3,681,856). Claims 3-5 are rejected under 35 U.S.C. 103(a) as being unpatentable over Aoki and La Pan, and further in view of Chen (US Patent No. 5,068,030). Claim 10 is rejected under 35 U.S.C. 103(a) as being unpatentable over Aoki and La Pan, and further in view of Dobson (US Patent No. 5,372,153).

Regarding to amended claim 1, the cleaning machine comprises a cleaning cistern, a drying unit, and a control device. The cleaning cistern comprises a microwave oven located in a bottom of the cleaning cistern and at least one shelf is located above the microwave oven for supporting the supporting trays. The drying cabinet comprises a frame comprising a plurality of heaters and at least one shelf for supporting the PCB supporting trays. The control device controls a cleaning process and a drying process of the cleaning machine. Wherein when the cover is rotated down to cover the main body the cleaning process starts, and after the cleaning process is completed the supporting trays are transferred to the shelves of the drying cabinet and the drying process starts.

NONE of Aoki and La Pan disclose such a cleaning machine can complete such a motion: when the cover is rotated down to cover the main body the cleaning process starts, and after the cleaning process is completed the supporting trays are transferred to the shelves of the drying cabinet and the drying process starts. NONE of Aoki and La Pan indicates such a combination as the current invention to provide an automatic, high efficiency and low-cost cleaning machine with functions of cleaning and drying. The combination is only a hindsight. Aoki

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disclose a wafer cleaning and rinsing apparatus. La Pan discloses a tray dryer. It is doubt that a person could put cleaned wafers into a tray dryer of La Pan to be dried. The two prior art references relate to two fields of endeavor which are irrelevant to each other. One can not determine obviousness by using the claims as a guide to collect prior arts necessary to reject the claims. In holding an invention obvious in view of a combination of references, there must be some suggestion, motivation, or teaching in the prior art that would have led a person skilled in the art to select the references and combine the in the way that would produce the claimed invention. Thus, claim 1 should not be deemed as obvious over the cited prior arts, and should be allowable.

Accordingly, claims 2-10 should be allowable since they include all limitations of claim 1.

Regarding to amended claim 17, the cleaning machine comprises a cleaning cistern, a drying cabinet, and a control device controlling a cleaning process and a drying process of the cleaning machine. The cleaning cistern comprises a frame with a plurality of heaters, and at least one fan located around an upper portion of the drying cabinet and enclosed in a vented shield. The drying cabinet comprises a frame with a plurality of heaters, and at least one fan located around an upper portion of the drying cabinet and enclosed in a vented shield.

NONE of Aoki and La Pan discloses such a combination as the current invention to provide an automatic, high efficiency and low-cost cleaning machine with functions of cleaning and drying. The combination is only a hindsight. Aoki disclose a wafer cleaning and rinsing apparatus. La Pan discloses a tray dryer. It is doubt that a person could put cleaned wafers into a tray dryer of La Pan to be dried. The two prior art references relate to two fields of endeavor which are irrelevant to each other. One can not determine obviousness by using

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the claims as a guide to collect prior arts necessary to reject the claims. In holding an invention obvious in view of a combination of references, there must be some suggestion, motivation, or teaching in the prior art that would have led a person skilled in the art to select the references and combine them in the way that would produce the claimed invention. Thus, claim 17 should not be deemed as obvious over the cited prior arts, and should be allowable.

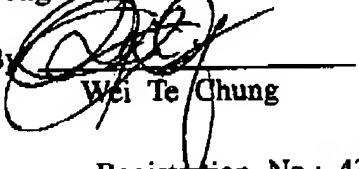
Accordingly, claim 18 should be allowable since they include all limitations of claim 17.

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